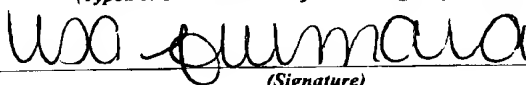


<b>CERTIFICATE OF TRANSMISSION BY FACSIMILE (37 CFR 1.8)</b>			<b>Docket No.</b> <b>14463</b>
Applicant(s): <b>Haruo Sunakawa, et al.</b>			
<b>Serial No.</b> <b>09/821,411</b>	<b>Filing Date</b> <b>March 29, 2001</b>	<b>Examiner</b> <b>S. Mulpuri</b>	<b>Group Art Unit</b> <b>2812</b>
Invention: <b>METHOD OF MANUFACTURING A NITROGEN-BASED SEMICONDUCTOR SUBSTRATE AND A SEMICONDUCTOR ELEMENT BY USING SAME</b>			
<p>I hereby certify that this <u>Response under 37 C.F.R. 1.116</u> (Identify type of correspondence)</p> <p>is being facsimile transmitted to the United States Patent and Trademark Office (Fax. No. <u>703 308 7722</u>)</p> <p>on <u>March 26, 2003</u> (Date)</p> <p style="text-align: right;"><u>Lisa Fiumara</u> (Typed or Printed Name of Person Signing Certificate)</p> <p style="text-align: right;"><u></u> (Signature)</p> <p style="text-align: center;"><b>Note: Each paper must have its own certificate of mailing.</b></p> <p style="text-align: right;">FAX RECEIVED MAR 28 2003 COMMUNICATIONS SECTION</p>			